

Laser Micromachining: A flexible tool in Vertical Probe Card Manufacturing

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Outline

1. Introduction to Laser Micromachining

2. Laser micro-Drilling capability

3. Laser Drilling for Vertical probe card manufacturing

4. Future Trends







Oxford Lasers

Laser Manufacturer & Laser System Integrator



Founded 1977, spin-off Oxford University Location: Oxford (UK), Boston (USA)

Main Areas of Activity:

- High-Speed Imaging
- Laser Micromachining
- Turn-key Laser Systems
- Proof-of-Concept Trials
- Contract R&D
- Sub-contract Manufacturing
- Collaborative Projects
- Lasers & Accessories

What is Laser Micromachining?



Laser Ablation - material removal by a combination of evaporation and melt expulsion.

Proportion of evaporation vs melt expulsion depends on laser parameters and material

Why Use Lasers?

Conventional

Wire Electro-Discharge (EDM) Mechanical Chemical milling Water Jet Ion Milling Electron Beam Punching

Low Drilling Speed = High Cost

Laser

Non-contact technique Soft Tooling Processing speed High Resolution Flexibility (hole size, shape) Compactness (footprint) Cost effectiveness



Benefits of Laser Drilling

- 1. Lasers can machine all industrial materials (plastics, ceramics, silicon, metals, glasses)
- 2. Small holes and high packing densities give end user more flexibility in design
- 3. Lasers can create any toolpath on a workpiece using a CAD/CAM interface (shaped holes possible)
- 4. Laser drilling systems are safe, easy to operate with minimal training and have minimal downtime
- 5. Future proof technology
- 6. Rapid turnaround due to soft tooling

Applications of Laser Micromachining



Cardiac stent manufacturing





Inkjet printer manufacturing



Industrial Laser Drilling Applications

Semi/Microelectronics

Inkjet Printer Nozzle PCB via interconnects Optical Switching Heat management in PCB packaging •IC Test Vertical Probe Card

Automotive

Fuel-Injection Nozzle Fuel Filter ABS Car brake sensors Con-rod lubrication

Environment/Ren.Energy

Toxic Gas Sensors Solar Cell Technology Fuel Cell Particulate Filters

Aerospace/Defence

Turbine component cooling Engine Silencing Missile guidance Aerofoil laminar flow

BioMedical MEMS

Catheter Sensors Aerosol Spray Atomisers DNA Sampling Vaccine production Lab-on-a-Chip Cardiac Stent Manufacturing

<u>Other</u>

Food Packaging Gem Stone drilling Digital Fingerprinting

Which Laser to use?



LASER	λ (nm)	Pulse width	PRF
DPSS	213-1064	ns-µs	1Hz- 200kHz
Copper	255,511	ns	kHz
Excimer	157-351	ns	1Hz- 1kHz
Ultrafast	390-1048	Fs-ps	1-5kHz



From P.R. Herman et al.rApplied Surface Science 154-155 (2000) 577-586

Important Parameters



Laser Micro-machining

Importance of correct choice of laser & process Holes in 1mm thick Steel



Optimum Laser Parameters Clean hole with no recast almost no debris



Non-Optimum Laser Parameters Significant recast, crown and debris

Laser Drilling Techniques



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Example of high-speed drilling



Fuel cell mesh



Total: 46,000 holes Drill speed:up to 250 holes/sec

DPSS ns Laser Ablation of Silicon



Single-shot Laser Ablation 355nm UV DPSS Max.Pulse Energy: 0.5mJ Spot size: 9µm Pulse Duration: 45ns M² <1.2

•UV ns DPSS lasers can provide high peak power due to diffraction limited small spot sizes on target

•Very high peak power helps drill silicon fast.

•Small holes down to 5µm can be achieved varying peak power with high aspect ratios >100:1

Silicon

UV ns Laser Trepanning Drilling



Femtosecond laser drilling



Example of laser machined channel and hole for micro-fluidic application



125 μ m Ø, 355nm, c-Si 350 μ m thick

- •Short (λ) or short (τ) lasers show superb result
- •No laser-induced thermal damage
- •No Particulate contamination

Special Ceramics

High aspect ratio microholes



Low thermal expansion ceramics

Difficult to process with conventional drilling

Polymers

504m 0004

Laser Optical Trepanning

355nm UV DPSS High quality,minimal HAZ



Blind-holes



Polymers

Laser Cutting

355nm UV DPSS High quality, minimal HAZ, sharp features





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IC Vertical Test Probe Card

Vertical probe heads used for IC electrical testing prior to packaging.

They require microholes to guide the contacting wires.

Laser drilling of the guide plates allows high packing density with smaller hole sizes and provides flexibility, high processing speed



Materials

Silicon ceramics plastics

Hole Geometry

Hole size : 40 - 100 μ m diameter Hole shape : square, circular, elliptical Hole Cylindricity : parallel or tapered Wafer thickness : 300-700 μ m

Technology challenges

Hole position accuracy Speed of drilling Taper angle control tolerance Toolpath flexibility, any hole shape

Ceramic MicroDrilling

500µm thick, 511nm

entrance 2.5kU X588 584M 888426 exit 90µmØ . 5kU X500 584m 888426 $\mathrm{Si}_3\mathrm{N}_4$



50µm Ø, 60µm pitch



Alumina 650µm thick



50µm square holes



Plastic MicroDrilling

15um hole, pitch 40um, 50um thick





Polyimide 500µm thick





135µm Ø

2-D Error Mapping Stage Calibration





HOLE POSITION ACCURACY IS PARAMOUNT.

We use:

- •High resolution, high position accuracy x-y stages
- Temperature controlled workstation
- •Wafer leveling and alignment equipment.

We calibrate all our stages against known National Physical Laboratory standards

Performance Evaluation Data

Example of 1000 laser drilled holes

Important!!

The hole size repeatability depends on:

- •Laser pulse-to-pulse stability
- Sample uniformity and surface texture
- •Sample levelling

The hole positioning accuracy depends on:

- •X-Y table accuracy
- Laser beam pointing

X-Y Table Positional Accuracy				
	X-AXIS	Y-AXIS		
std.dev	0.56	1.05		
Ср	4.8	2.5		
Cpk	1.65	1.4		

Hole Size Repeatability







Machine Vision & Alignment

Wafer levelling and alignment is critical for –µm level position accuracy in laser hole drilling.

•High resolution cameras and onaxis position sensitive detectors are used to align the wafers.

Laser-drilled hole size measurement and inspection can be performed insitu with user-friendly digital imaging analysis software with custom recipes.





ProbeDrill™





Output Power[W] • Stop Oscillator Laser Off Start Oscillator Interlock Set Power(W) Delay offset (nS) Output Power(W Laser Off Stop Lock power Amplifie Amplifier Interlock Beam ON Delay Hold

Laser

Proprietary Optical Trepanning System

5-axis part positioning

Material handling systems (options)

User-friendly pc interface

Future Trends in Laser Hole Drilling

Better Resolution

(shorter wavelength, 2nd, 3rd, 4th harm DPSS)

Lower Production Cost

(proc.speed, high rep.rate, high power)

Better Quality

(shorter pulses, motion control speed)

More Complex Materials

(multi-wavelength laser systems)

Industrial Robustness

(compact, fully diode-pumped laser systems)

Summary

•Laser micromachining is a well established industrial processing method

 Lasers can process all commonly used materials in the wafer test arena

•Laser microdrilling is a flexible tooling technique

•Lasers coupled with ultra accurate motion tables offer competitive advantages for vertical probe card manufacturing

 Lasers are an enabling technology – Smaller features in difficult to process materials

Thank You

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